

MSI-1

JC974 U.S. PTO
09/776009
02/02/01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Michael A. Vyvoda et al.
For : WAFER SURFACE THAT FACILITATES
PARTICLE REMOVAL
Serial No. : To Be Assigned

Hon. Assistant Commissioner
for Patents
Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Sir:

In accordance with 37 C.F.R. §§ 1.56, 1.97, and
1.98, applicants wish to call the attention of the Examiner
to the following documents:

U.S. Patents

Johnson et al.	6,034,882	03/2000
Zhang	5,835,396	11/1998

These documents are listed on the accompanying
Form PTO-1449 (submitted in duplicate) and copies are
enclosed herewith.

Consideration of the foregoing in relation to this
patent application is respectfully requested.

Respectfully submitted,



Steven J. Cahill
Reg. No. 44,578
Attorney for Applicants
FISH & NEAVE
1251 Avenue of the Americas
New York, New York 10020-1104
Tel.: (650) 617-4000

c/o